

FIGURE 1



FIGURE 2

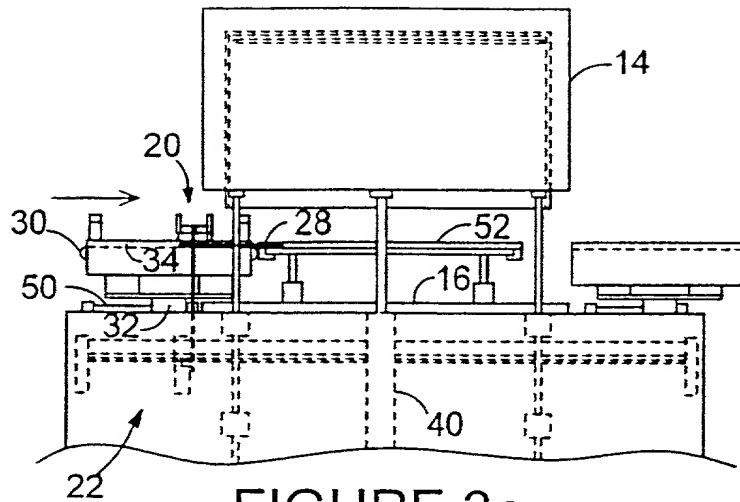


FIGURE 3a

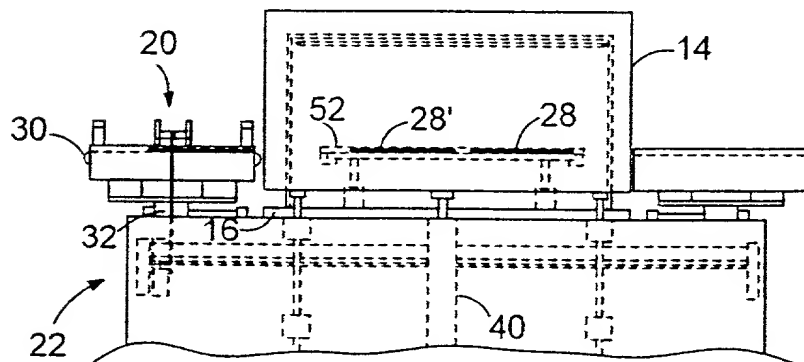


FIGURE 3b

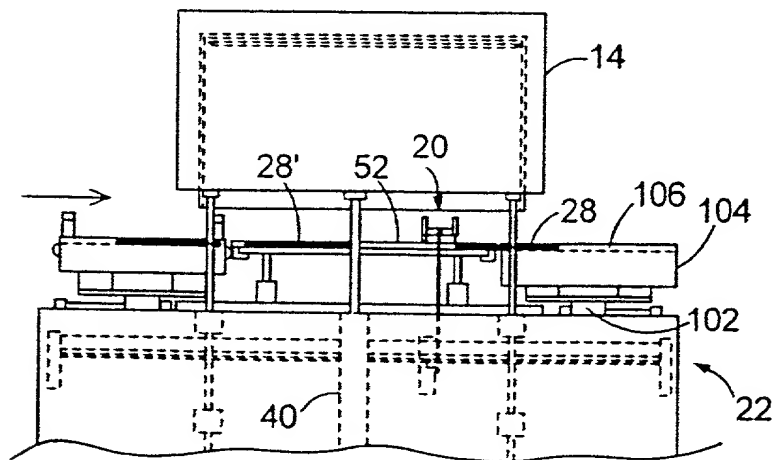


FIGURE 3c

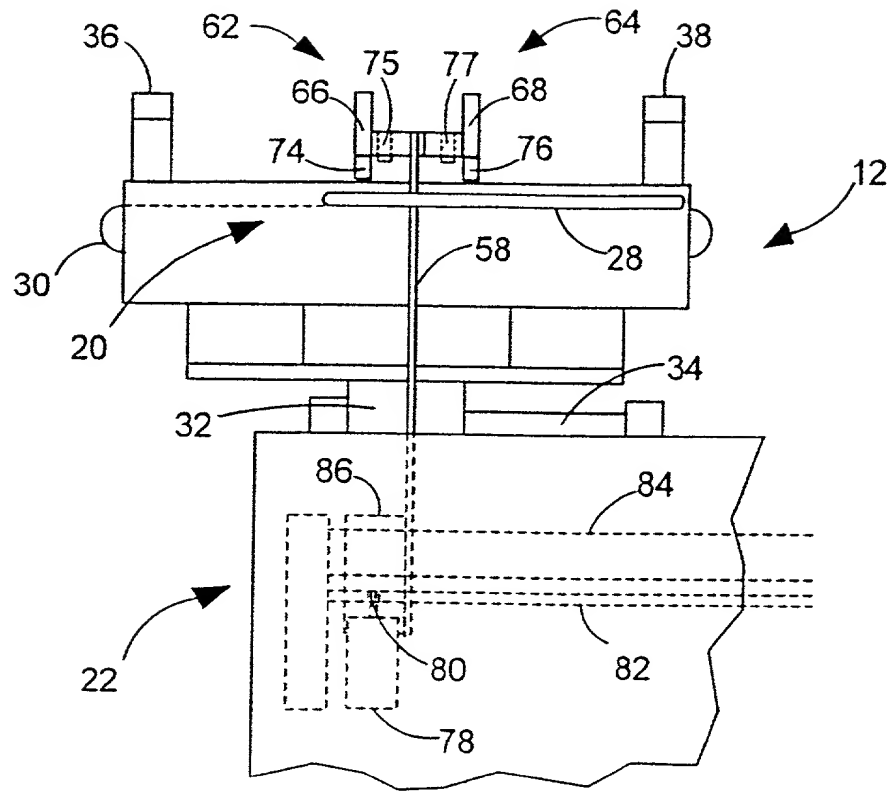


FIGURE 4

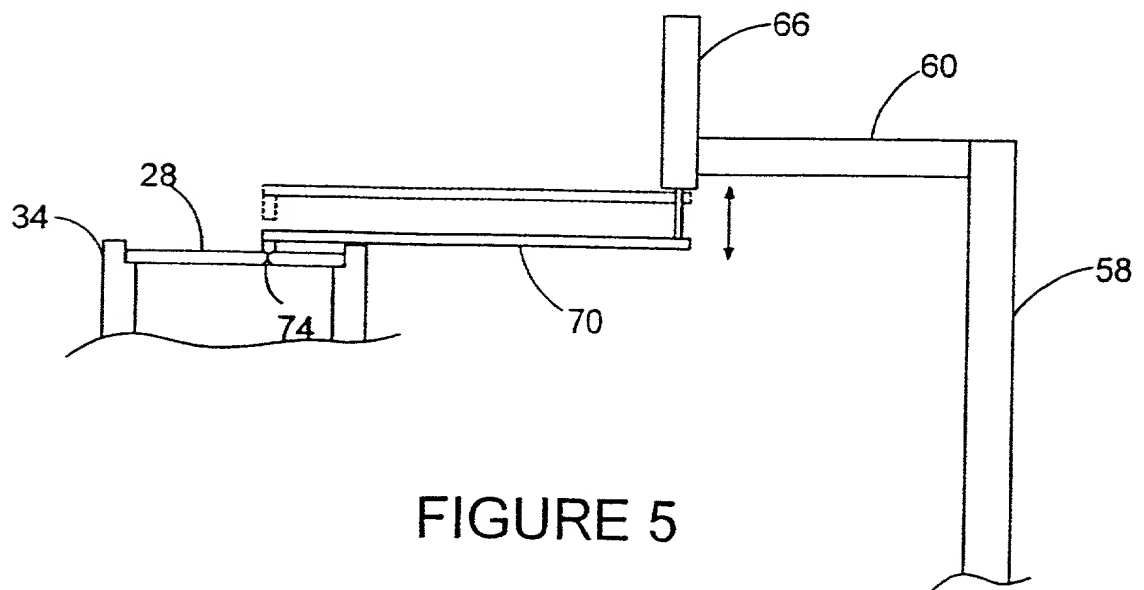


FIGURE 5



FIG. 6 is a schematic diagram of a system 100 for processing a substrate 28. The system 100 includes a substrate holder 110, a processing chamber 112, a gas inlet 114, a gas outlet 116, a gas supply 118, a gas control system 120, a gas monitor 122, a gas filter 124, a gas purifier 126, a gas recycler 128, a gas vent 130, a gas detector 132, a gas alarm 134, a gas shutdown 136, a gas reset 138, a gas test 140, a gas calibration 142, a gas maintenance 144, a gas repair 146, a gas replacement 148, a gas disposal 150, a gas storage 152, a gas transport 154, a gas distribution 156, a gas collection 158, a gas removal 160, a gas extraction 162, a gas separation 164, a gas purification 166, a gas refinement 168, a gas conversion 170, a gas transformation 172, a gas modification 174, a gas alteration 176, a gas adjustment 178, a gas optimization 180, a gas enhancement 182, a gas improvement 184, a gas upgrade 186, a gas update 188, a gas upgrade 190, a gas update 192, a gas upgrade 194, a gas update 196, a gas upgrade 198, a gas update 200.

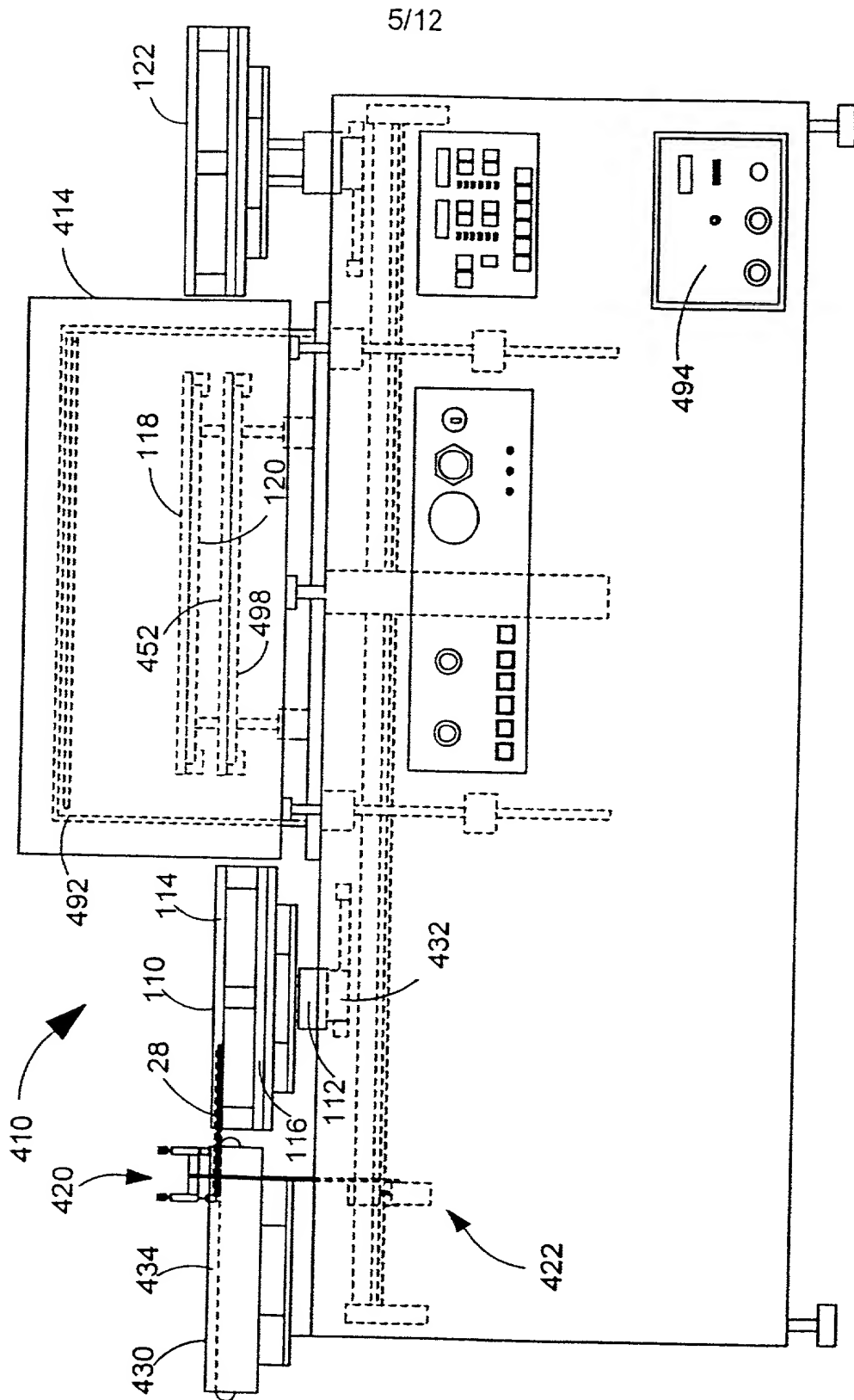


FIGURE 6

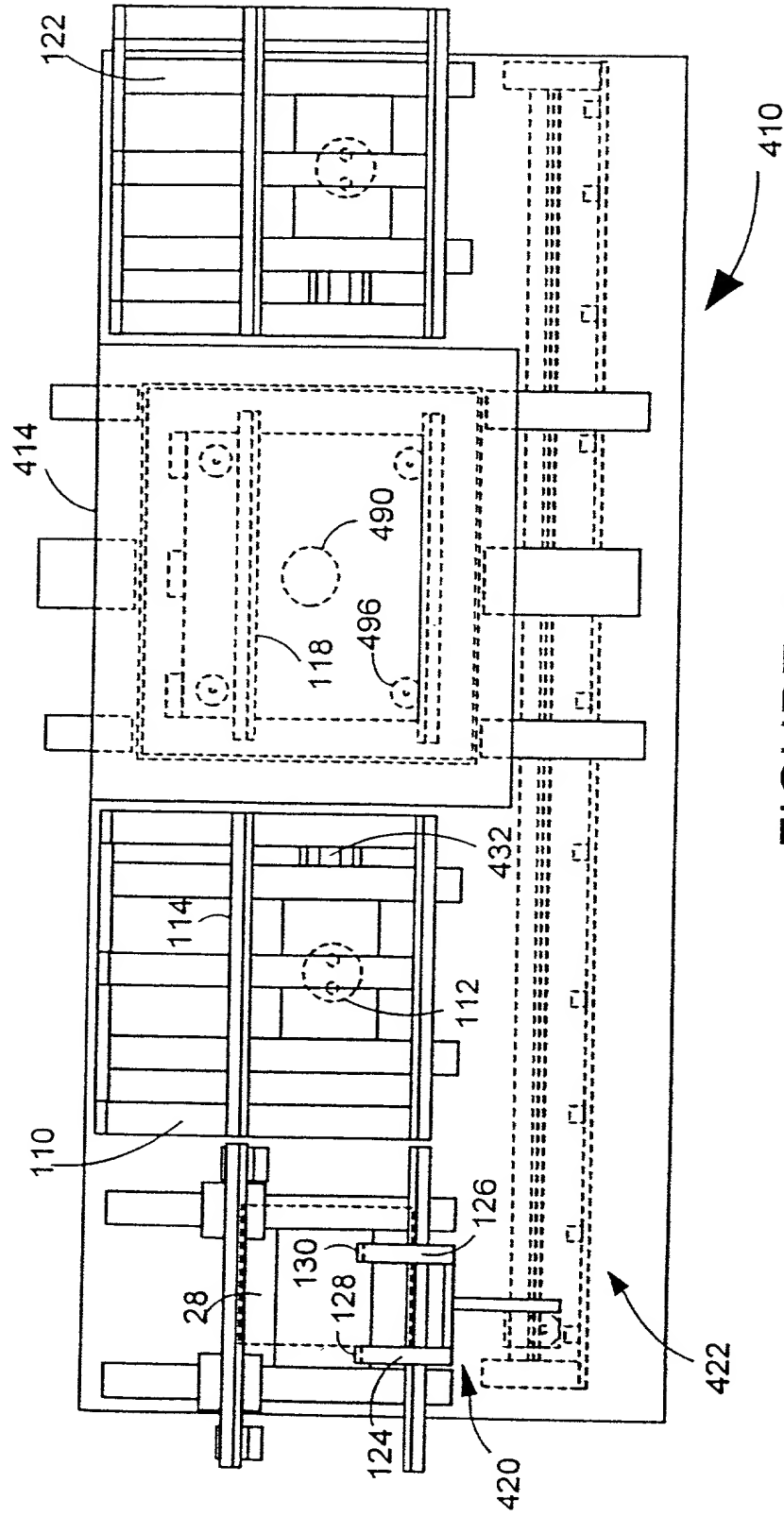


FIGURE 7



7/12

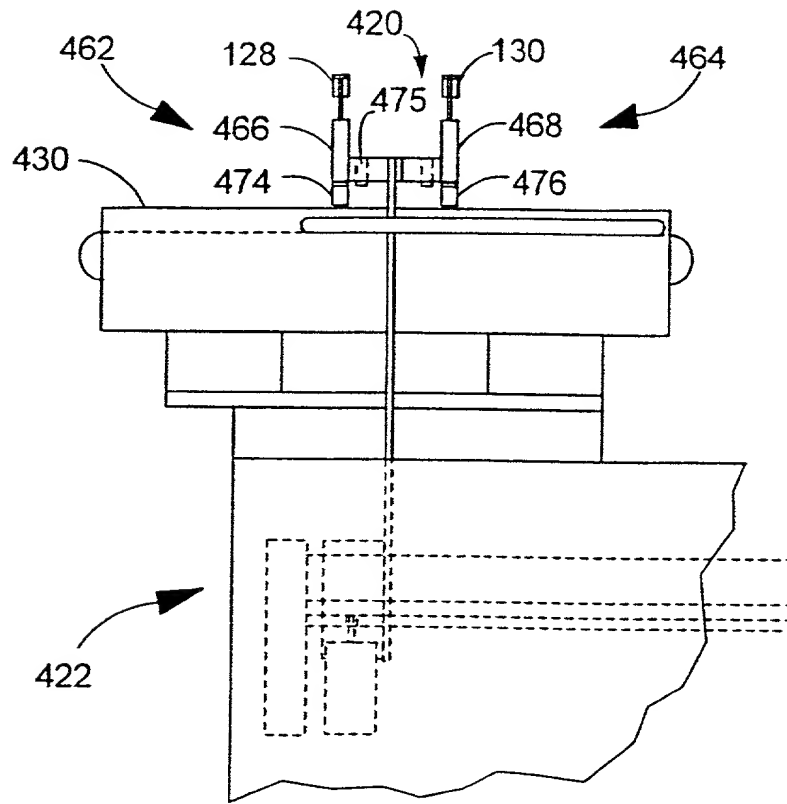


FIGURE 8

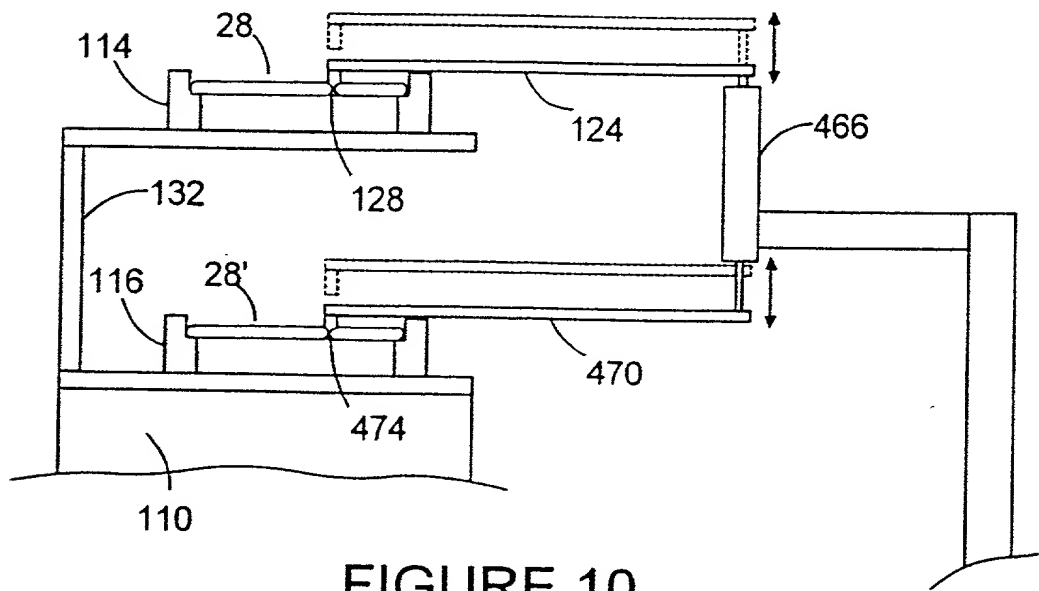


FIGURE 10



FIGURE 9a

8/12

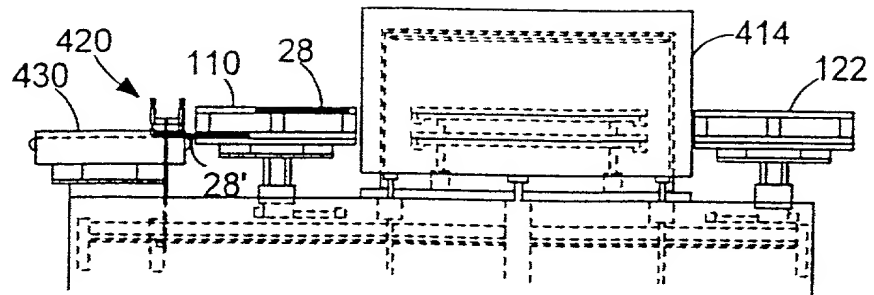


FIGURE 9b

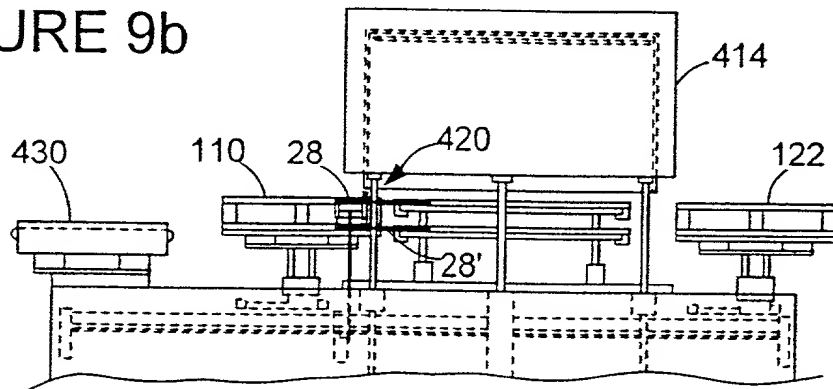


FIGURE 9c

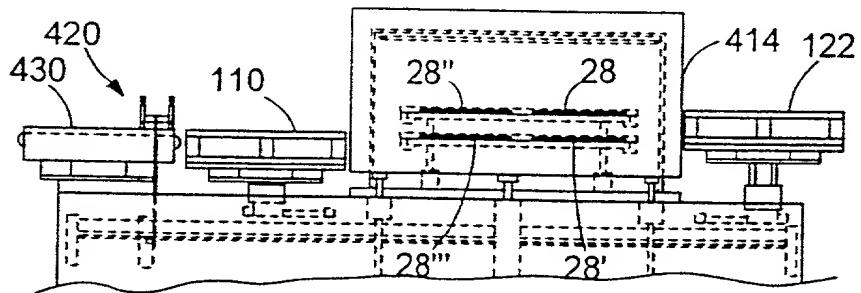
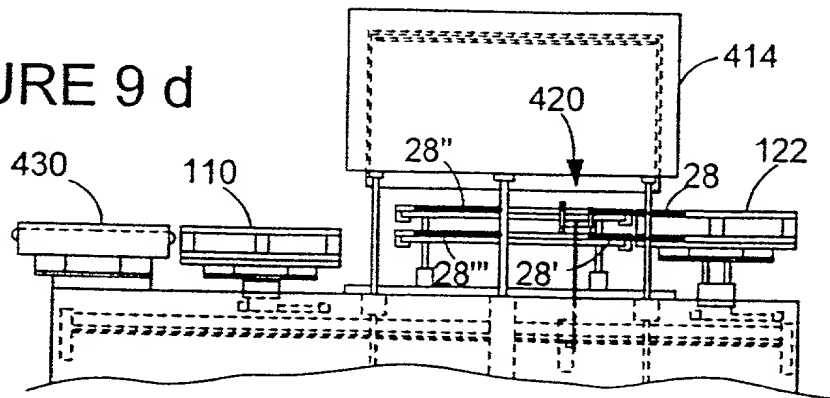


FIGURE 9 d



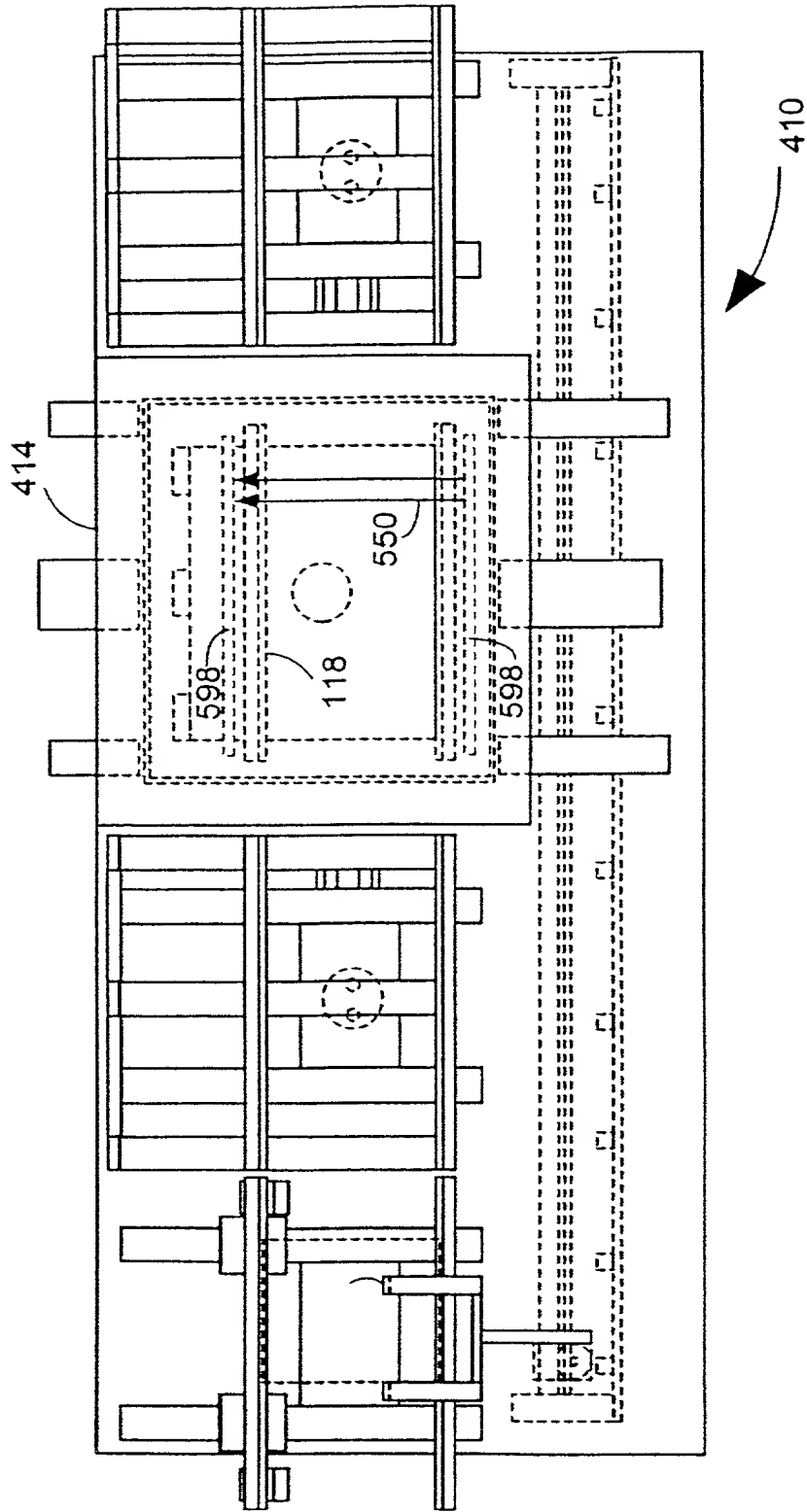


FIGURE 11

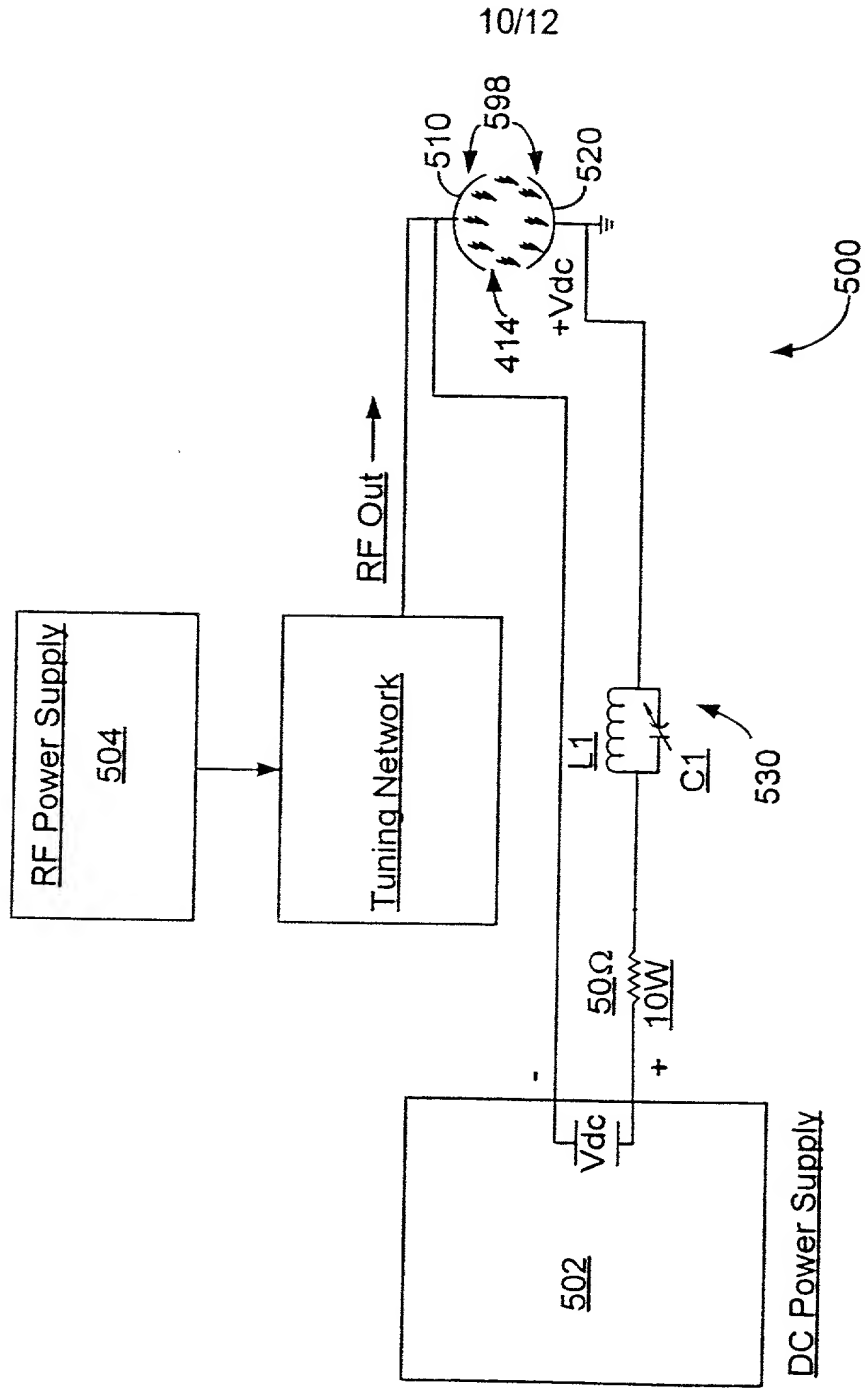
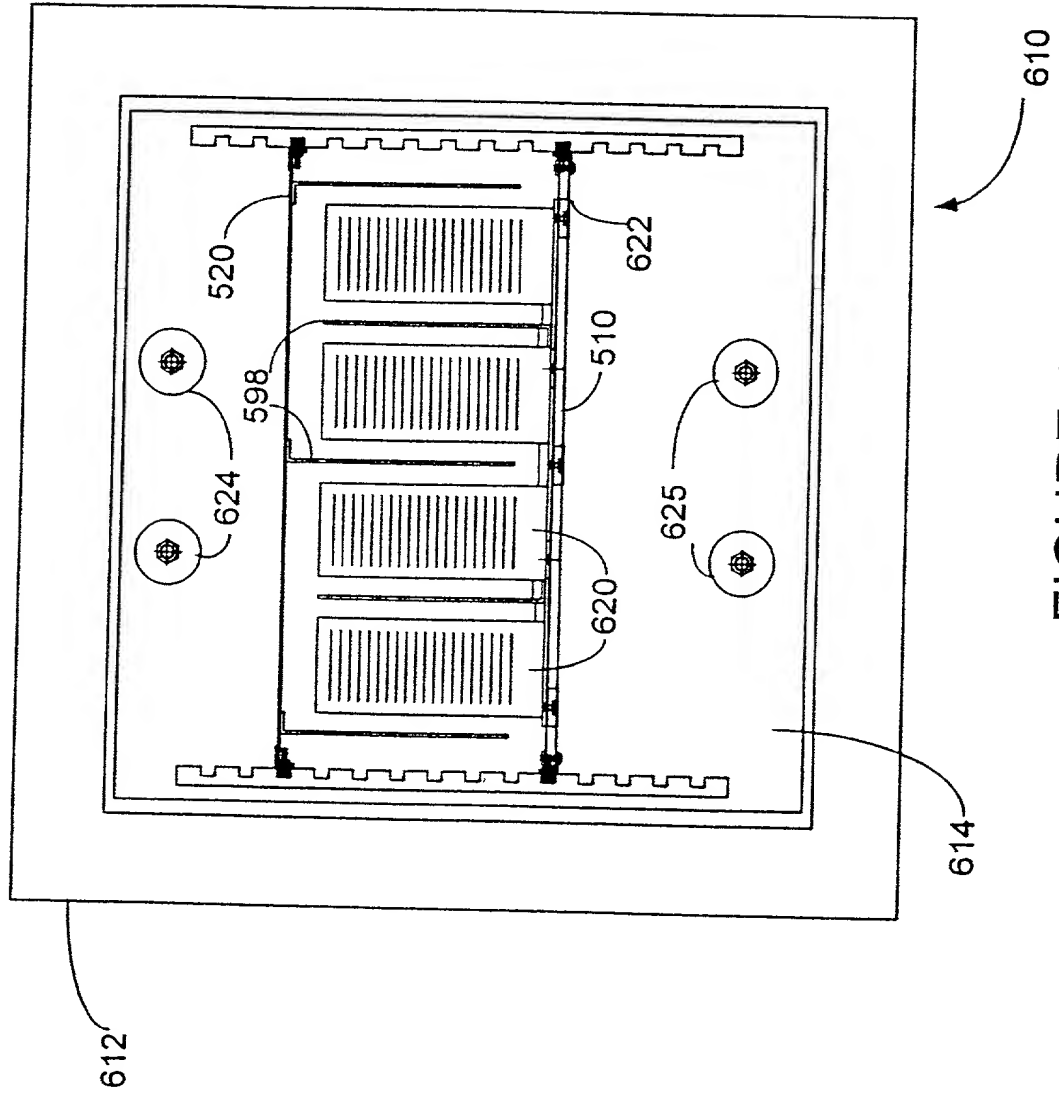


FIGURE 12



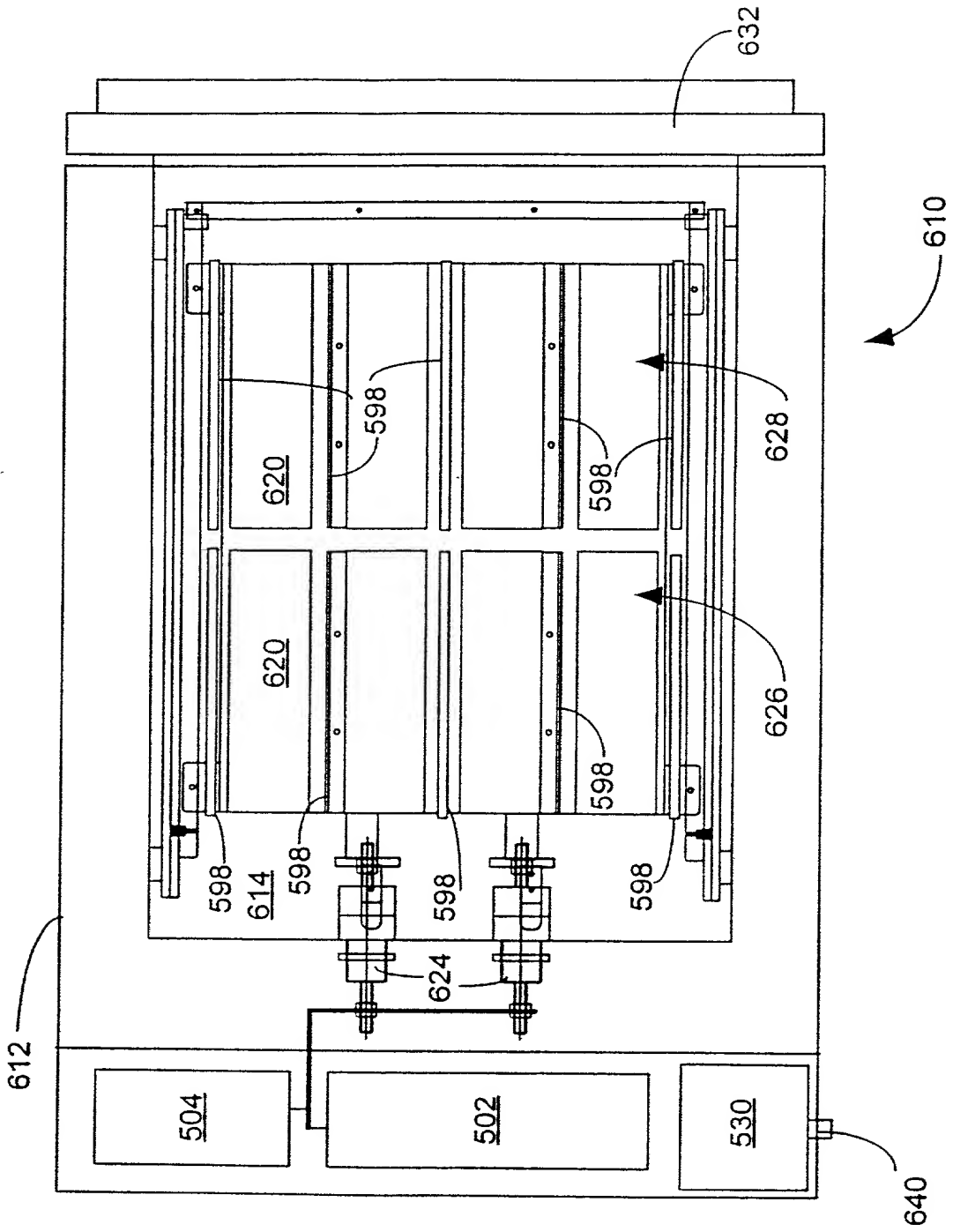


FIGURE 14